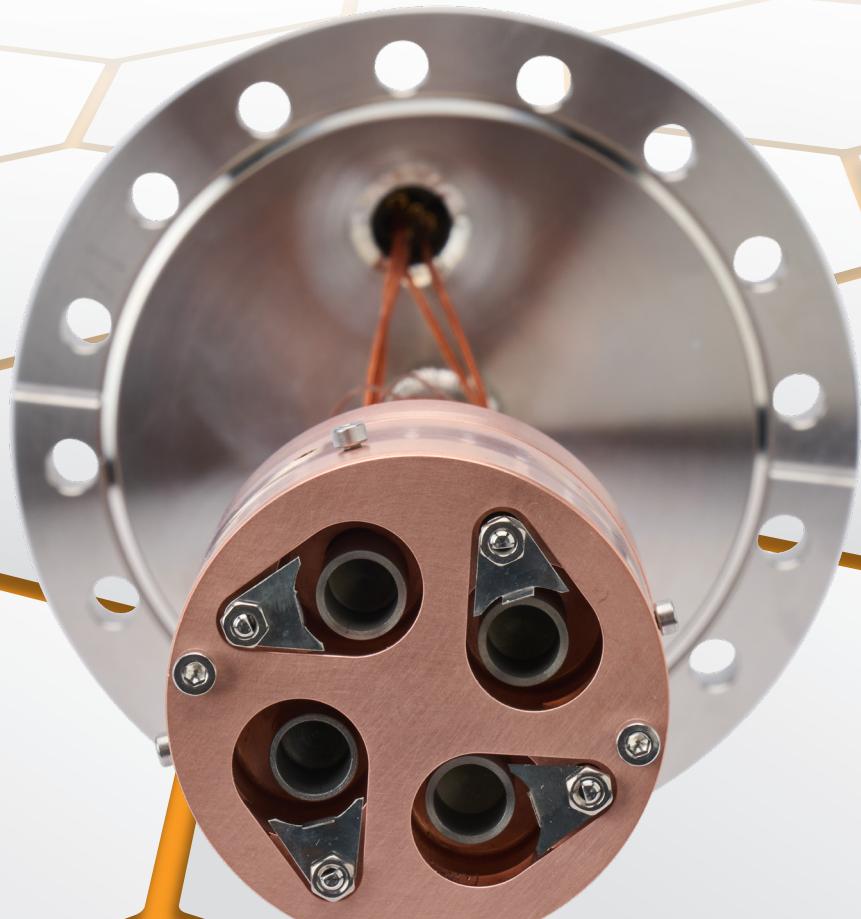




**KORVUS TECHNOLOGY**

**TAU-UHV**

FOUR-POCKET  
ELECTRON BEAM  
EVAPORATION SOURCE



**WWW.KORVUSTECH.COM**

Designed & Manufactured in the United Kingdom

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# TAU-UHV

The TAU-UHV is a UHV-compatible four-pocket electron beam evaporation source for thin-film deposition.

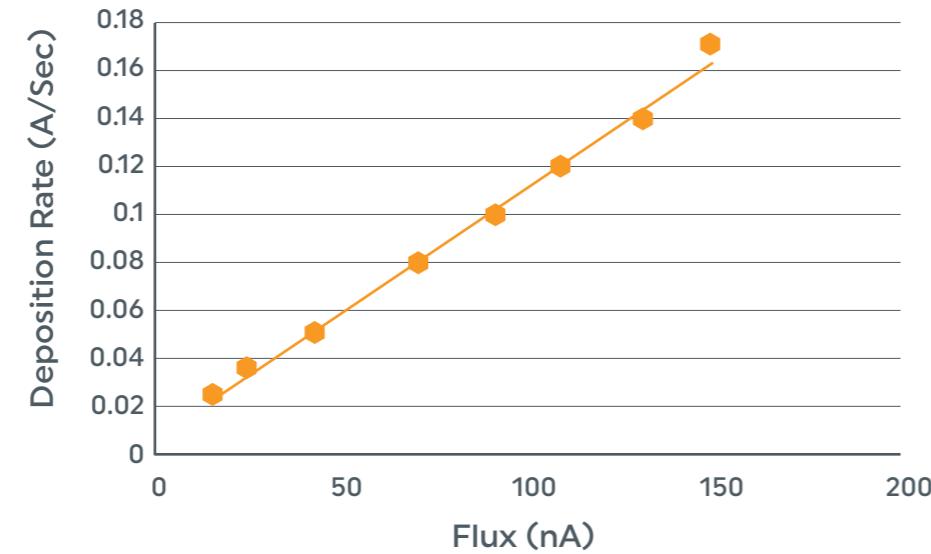
Configurable to different flange sizes and angles, the TAU-UHV can be fitted to any existing deposition system.

A compact and powerful tool for evaporating metals, the TAU-UHV can evaporate up to four pockets simultaneously or sequentially.

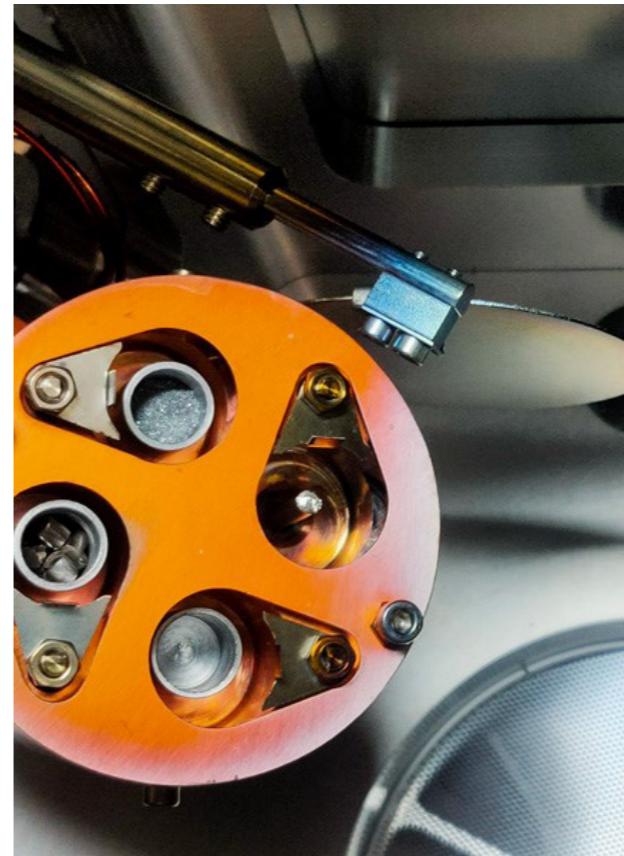
Each pocket can be equipped with crucibles or rods. Crucibles can also accept ceramic liners which are recommended for use with several materials. Korvus Technology supply a wide range of crucible options to cater for most materials and applications and will advise users on the right choice for a given evaporant.

The sources are equipped with flux monitoring electrodes above each pocket to allow independent monitoring and regulation of the deposition rate. This technique capitalises on the phenomenon whereby a small fraction of the vapour emerging from the evaporant is ionised and that this fraction shows a linear relationship with vapour pressure in the beam.

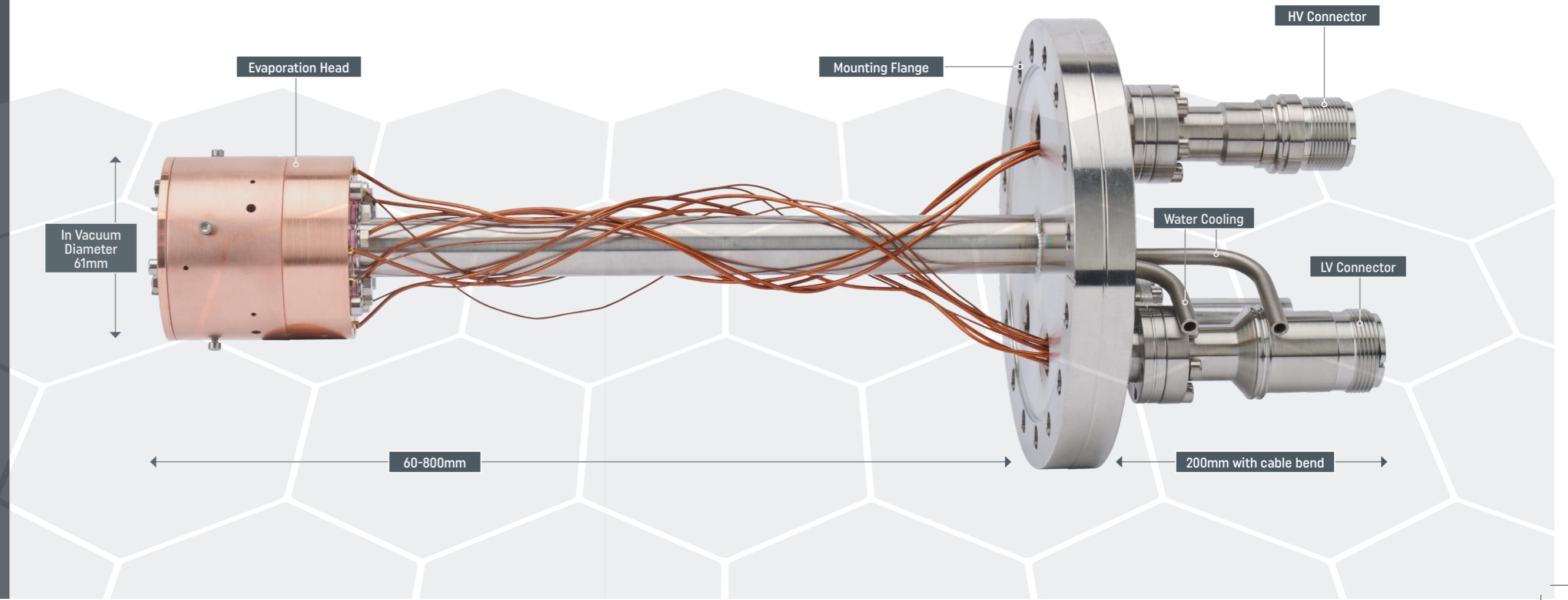
Once calibrated, this ion current can therefore be used as an independent guide to deposition rate and is sensitive even at rates far below the sensitivity levels of quartz-crystal thin film monitoring devices.



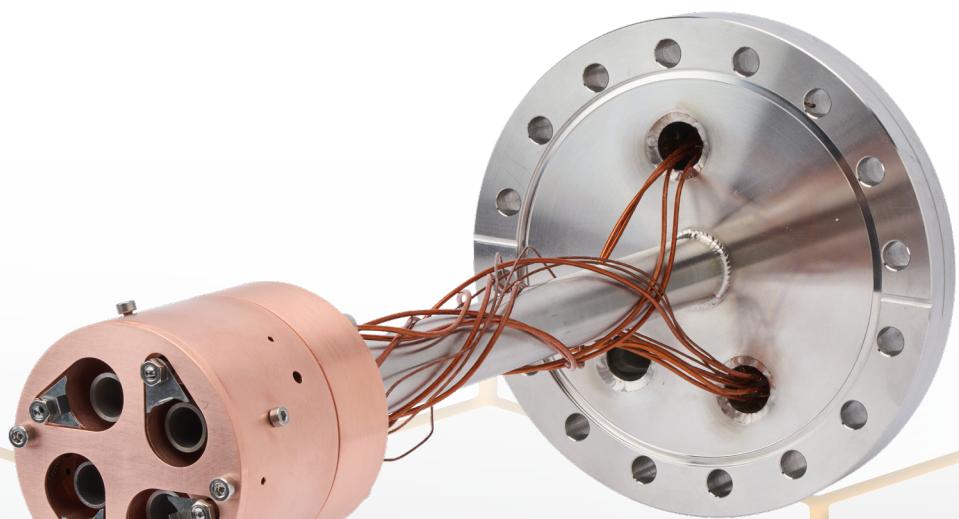
The graph showing the principle and relationship between deposition rate of molybdenum, as measured by a quartz-crystal monitor and the ion current (flux) measured on the flux-monitoring plate of a TAU-UHV source.



Features	
Mounting Flange	From CF63
In-vacuum length	60-800mm
In-vacuum diameter	61mm (smaller diameter available on request)
Pockets	4
Co-evaporation	Yes
Cooling	Water (0.5L/min)
Rack space	3U
Bakeout temperature	250°C
Input:	Single Phase, 100-240V, 50/60Hz



Korvus Technology has over 20 years' experience in the high and ultra-high vacuum sector. With over 150 HEX Series systems installed worldwide, Korvus Technology remains at the forefront of the PVD industry. Korvus is now part of the Judges Scientific group, while remaining an autonomous company. This allows Korvus to remain agile to the research challenges of its customers and continue its customer focused culture.



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